Supplemental Document

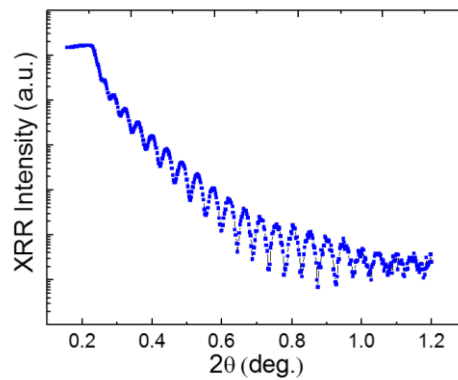
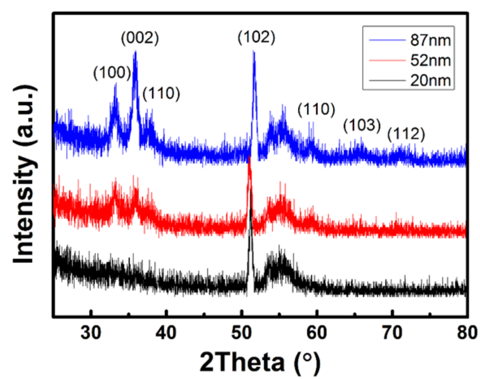


Fig.1 The measured curves of x-ray reflectivity measurements from the AlN films on Si(100) substrates.



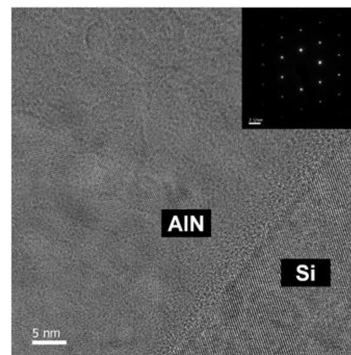


Fig.2 (Left) GIXRD patterns for different thick AlN films on Si (100) at 300 ℃. (Right) High-resolution cross sectional TEM images. The inset is the SAED patterns around the interface between AlN and Si.